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Dr. Ling Xie obtained her Ph. D degree from the University of Wisconsin-Madison in Materials Science and Engineering in 1994. She then became a post-doctoral researcher at Northwestern University. Before joining CIMS at Harvard University in 2004, Dr. Xie worked in industry and university research laboratories for more than ten years, including Eastman Kodak Cooperation, Bell Laboratories of Lucent Technologies, and Lehigh University. Her current work is focused on thin-film deposition, dry and wet etching, and advanced lithography.

Her expertise encompasses thin film deposition and characterization in the application of MEMS devices, bioengineering sensors, fluidic inkjet printing heads, high-k dielectrics, and MR/GMR transducers.

As a research scientist in Eastman Kodak from 1997 to 2000, Dr. Xie developed passivation layers that improved the reliability of MEMS-based fluidic inkjet printing heads. She also let engineer teams to implement new light-shield materials into imaging sensors for better image quality and manufacturing yield.

In 2001, she became a Member of Technical Staff in Bell Laboratories of Lucent Technologies, where she joined the 3D MEMS optical switch team and actively involved in the design and fabrication of micro-mirrors.

At Lehigh University from 2002 to 2003, Dr. Xie was responsible of searching high-dielectric gate materials for the next generation of CMOS devices. She also conducted studies on MEMS-based biology sensors and investigated the feasibility of Er-doped Si lasers.

Dr. Xie has published 15 journal and conference papers and is a member of Materials Research Society (MRS) and Nano Science and Technology Institute (NSTI).